FORM PTO-1449 U.S. DEPARTME' 'OF COMMERCE Atty Docket: ADACHI P163USP2 Examiner: John ffmann (Rev.2-32) PATENT AND TRADEMARK OFFICE Group: 1731 INFORMATION DISCLOSURE Applicant: Akira IKUSHIMA, Kazuya SAITO, Takashi STATEMENT BY APPLICANT MIURA and Shogo NASUDA (Use several sheets if necessary) U.S. PATENT DOCUMENTS Examiner Document Sub-Filing Date, loitial Number <u>Name</u> if Appropriate 4,028,080 Di Vita <u>Jun. 1977</u> 4,157,253 <u>Jun. 1979</u> <u>Hema**u**rsi</u> 4,182,664 Jan. 1980 <u>Maklad</u> 5,267,343 Nov, 1993 <u>Lyons</u> Apr. 1997 5,620,496 <u>Erdogan</u> 5,983,673 Nov. 1999 <u>Urano</u> 6,058,739 May 2000 Morton 5,478,371 Dec. 26, 1995 <u>Lemaire et al</u> FOREIGN PATENT DOCUMENTS Examiner Document Sub-Translation Number Country Date Class 0 687 924 A1 Dec. 20, 1995 **EPO** 2808457 Aug. 1974 <u>Germany</u> 4-342427 4-342436 nsost 6-199539 · <u>Jun. 7, 1994</u> <u>Japan</u> <u>52-94657</u> Nov. 1993 <u>Japan</u> 54-134721 Oct. 1979 <u>Japan</u> 57-188423~ Nov. 1982 <u>Japan</u> 57-191247 Nov. 25, 1982 <u>Japan</u> 60-200204 Oct. 9, 1985 <u>Japan</u> 61-45201 Mar. 5, 1986 <u>Japan</u> 05-288942 Nov. 5, 1993 <u>Japan</u> 09-230048 Sep. 5, 1997 <u>Japan</u> 01-316445 Dec. 2, 1998 <u>Japan</u> 11-029335 Feb. 2, 1999 <u>Japan</u> OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.) "Thermal Annealing of Defects Indused by Art Excimer Laser Irradiation in a SiO2"; Japanese Society of Applied ROTHSCHILED, Mordechai, Daniel J. EHRLICH and David C. SHAVER, "Eximer Laser Induced Damage in Fused Silica", Microelectronic Engineering 11, 1990, pp. 167-172 "Temperature Dependence of the E' Center Creation in Silica Glasses", Physica Status Solidi (b), vol. 147,